

**PLASMA REACTOR HAVING RF POWER APPLCIATOR AND A DUAL-PURPOSE  
WINDOW**

**ABSTRACT OF THE INVENTION**

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In a plasma reactor including a reactor chamber, a  
workpiece support for holding a workpiece inside the chamber  
during processing and an inductive antenna, a window  
electrode proximal a wall of the chamber, the antenna and  
10 wall being positioned adjacently, the window electrode  
being operable as (a) a capacitive electrode accepting RF  
power to capacitively coupled plasma source power into the  
chamber, and (b) a window electrode passing RF power  
therethrough from said antenna into the chamber to  
15 inductively couple plasma source power into the chamber.